

Do Not Enter /K.K./

AMENDMENT UNDER 37 C.F.R. § 1.116
EXPEDITING PROCEDURE
EXAMINING GROUP 2800

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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| Applicant: | Van Beek, <i>et al.</i> | Docket No.: | EPC-019 |
| Serial No.: | 10/578,026 | Art Unit: | 2829 |
| Filed: | March 13, 2007 | Examiner: | Karen M. Kusumakar |
| | | Conf. No.: | 4725 |
| For: | Method of Manufacturing a MEMS Device and MEMS Device | | |

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT UNDER 37 CFR § 1.116

Dear Sir:

Applicant respectfully submits the following amendments and remarks in response to Examiner's Office Action dated March 5, 2009, which Action is made final. Applicant respectfully requests that these amendments and remarks be entered in pursuant to the provisions of 37 CFR § 1.116, and respectfully request reconsideration of the claims.